

Ion Beam Source IBS - 145



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The small-sized ion source IBS - 145 is a gas-discharge ion source, a hollow rectangular beam, the principle of operation is an accelerator with an anode layer (UAS) for a wide range of applications: ion cleaning, ion etching, ion polishing, ionic surface modification, assisted deposition.

Parameter	Value
Supply voltage	1500...5000 V
Average ion energy	<i>approx half supply voltage</i>
Maximum beam current	250 mA
<i>For working gas - argon, at a flow rate of not more than</i>	<i>2.0 l / h</i>
Beam shape	rectangular, hollow
Beam size (L x W x T) <i>Length x Width x Thickness</i>	120 x 42 x 5 mm
<i>At a distance of at least 200 mm from the source</i>	
Working pressure range	0,001 ... 10 Pa
Weight no more	3 kg
Max. operating voltage	5500 V
Max. operating current	350 mA
Max flow rate of working gas	1,5 - 2, 0 l / h
Min coolant consumption	1 l / min

It is produced in several versions.

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main dimensions, versions

